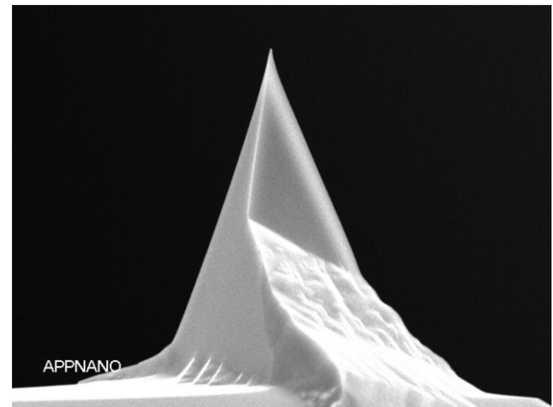
TiN-ACT

- Electrical Force Microscopy (EFM)
- Kelvin Probe Force Microscopy
- Conductive AFM (C-AFM)
- Piezoresponse Force Microscopy (PFM)
- Scanning Spreading Resistance Microscopy (SSRM) on polymer samples

Tip Specifications



- **Coating**: TiN (50 nm)
- **Material**: Silicon

Shape: Tetrahedral

- **Height (µm)**: 14-16
- **ROC (nm)** : 30

TiN-ACT
On click zoom images
Download Spec

Cantilever Specifications

Material	:Silicon
Shape	:Rectangular
Reflex coating	:Al (50 nm)

Parameter	Nominal	Min	Max
k (N/m)	37	13	77
f (kHz)	300.0	200.0	400.0
Length (µm)	125.0	115.0	135.0
Width (µm)	30.0	25.0	35.0
Thickness (µm)	4.00	3.50	4.50